Multiscale Robotics Architecture for Micro & Nano Manufacturing

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 Measure or predict how what we do at large scales affects the smaller scales (top-down).

 Follow a specific set of top-down design principles while designing manufacturing cell and parts.

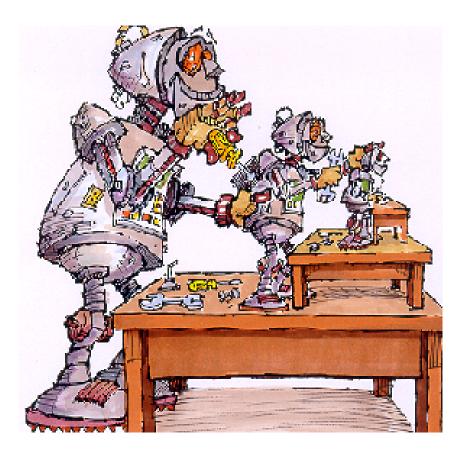


What is Multiscale Robotics?

Robotics where the size or tolerance of parts cuts across multiple scales Macro-Meso-Micro-Nano

Related terms

- Precision robotics
- •Top-down manufacturing
- Hierarchical manufacturing





Multiple Scales

- Nano Part sizes below 500nm, positioning accuracy below 250nm, SEM/TEM.
- Micro Part sizes between 0.5 µm and 500 µm, accuracy between 0.25 µm and 2.5 µm, optical microscope.
- Meso Part sizes between 500 µm and 5 cm, accuracy between 2.5 µm and 25 µm, regular optics.
- Macro Part sizes greater than 5 cm, accuracy greater than 25 µm, regular optics.



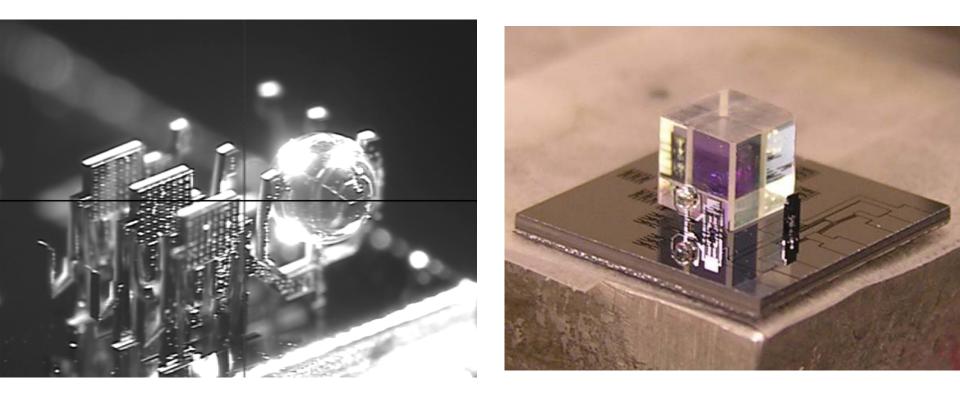
Assembly at Different Scales

Assembly scale	Mesoscale	Microscale	Nanoscale
Attribute			
Positioning	Easy	Difficult	Very difficult
Velocity	Cm/s or m/s are not unusual	Slow (µm/s), or (mm/s), vibration suppression	Very slow Nm/s, or μm/s
Force Sensing and Control	Easy / Necessary to avoid part damage and improve manipulability.	Difficult, The range of forces to be sensed could be as low as μN .	Difficult, AFM (atomic force microscope) is used to measure force.
Dominant forces	Gravity, Friction	Friction, Surface forces (stiction, electrostatic, Van der Waals)	Molecular/Atomic forces
Throughput	Serial assembly provides adequate throughput.	Serial assembly is usually not sufficient. Parallel manipulation methods are preferred.	Parallel manipulation methods, or self-assembly are necessary.
Gripper	Mechanical, many examples, RCC, Utah/MIT hand, etc.	Micromechanical, gripper-free manipulation preferred.	Other, optical, proximity force, etc.
Fixturing	Mechanical	Micromechanical fixturing must be used	Chemical
Compliance	Gripper compliance is not necessary if force is measured.	Gripper compliance is usually necessary.	Mechanical compliance does not apply.
Vision	Easy	Difficult (expensive optics)	Impossible in visible wavelengths.



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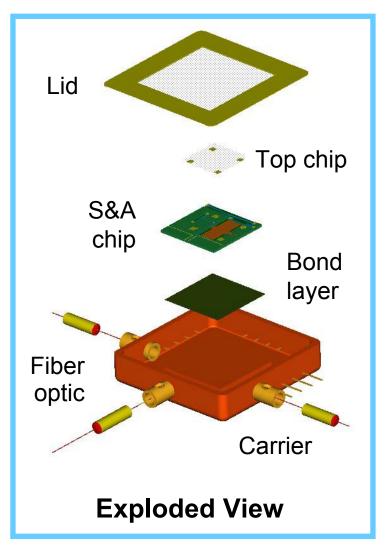
Assembled Microspectrometer

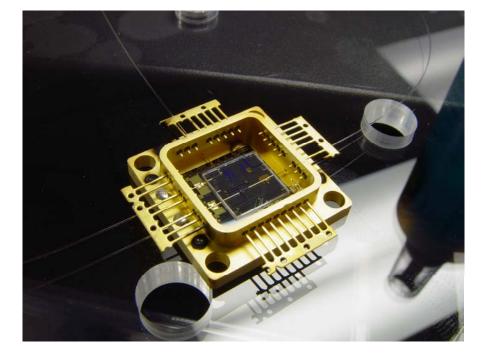


1 cm² die, 3x 500 μ m tall mirrors, 400 μ m ball lens, 3 mm² beamsplitter, MEMS scanning mirror [Lee06]



Microassembly of Fuzing Device











With KAIST and Hanson Robotics Inc.



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Low-Volume MEMS Packaging

- Packaging defined as assembly (manipulation) + process (bonding, sealing, etc.)
 - Multitude of commercially available and custom equipment. Generally, commercially available equipment is expensive, lacks versatility, modularity, reconfigurability.
- Create hardware & software to handle process and manipulation of microcomponents allowing:
 - Modularity and reconfigurability in hardware and software.
 - Provide a number of standard process capabilities.

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Small Scale Robotics

Design principles for system architecture

- Coarse-fine positioning for multiscale manipulation.
 - Range of fine motion > resolution of coarse motion.
 - Bandwidth of fine motion > resonance of coarse motion.
- Assembly tolerance and precision achieved through fixtures, calibration and servoing.



Small Scale Robotics (continued)

- Use grippers, fixtures or force fields to constrain parts at all times.
- Compliance at micro/nano scale, stiffness at macro/meso scale.
- Close the loop between scales using direct measurements (position, force).
- Affect vibration and motion at lower scales by input shaping at the upper scales.

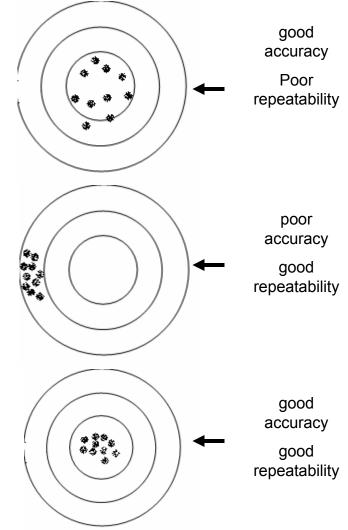


Precision Concepts

<u>Resolution</u>: smallest position increment that motion system can perform

<u>Repeatability</u>: ability to achieve desired position over many attempts

<u>Accuracy</u>: maximum difference between te actual and desired position





M³ Packaging System: Macro-Meso-Micro



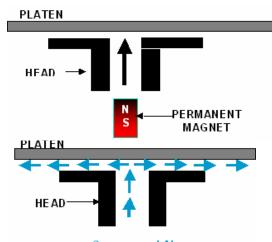
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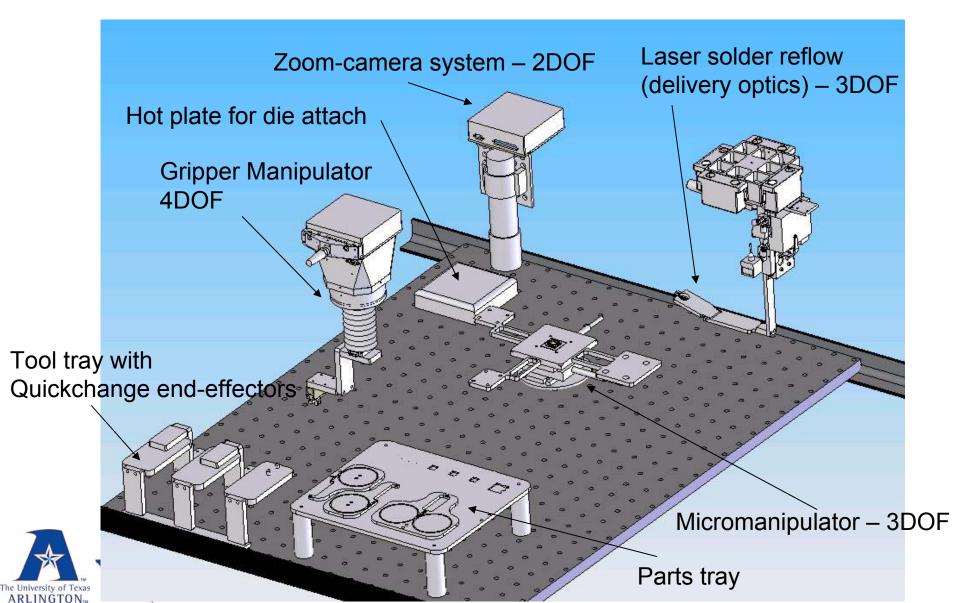
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•Multiple Robots within Motoman's Robotworld® Framework
•Platen usage: positioning surface for multiple endeffectors (pucks)
•Pucks: Linear motors riding on 15 μm air bearing

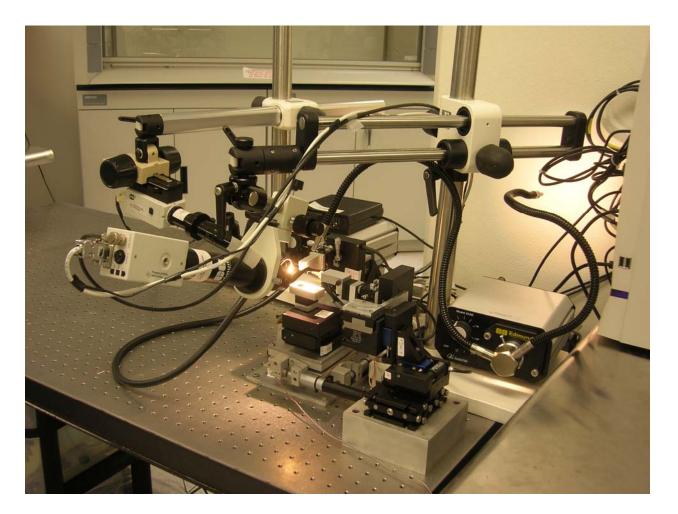


Compressed Air

M³ System Diagram



μ³ Microassembly Station: Meso-Micro-Nano



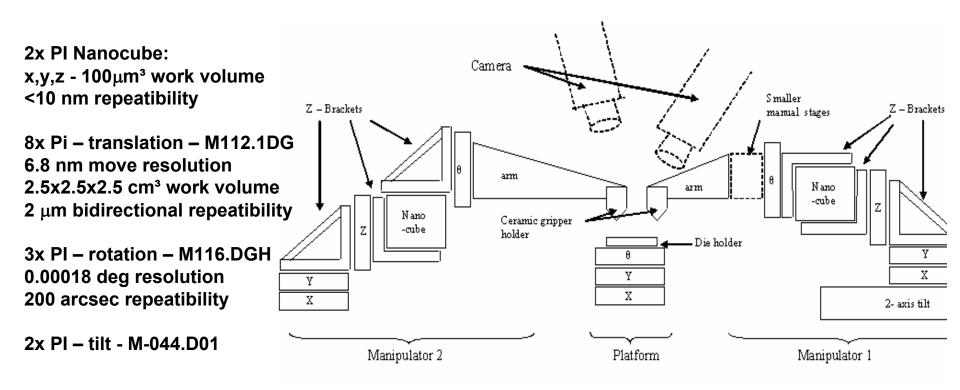
Consolidate controls via Labview® Interface from single PC

- Gripper Mounting
- Rotation Centering
- Calibration
- Visual Servoing



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μ³ System Diagram

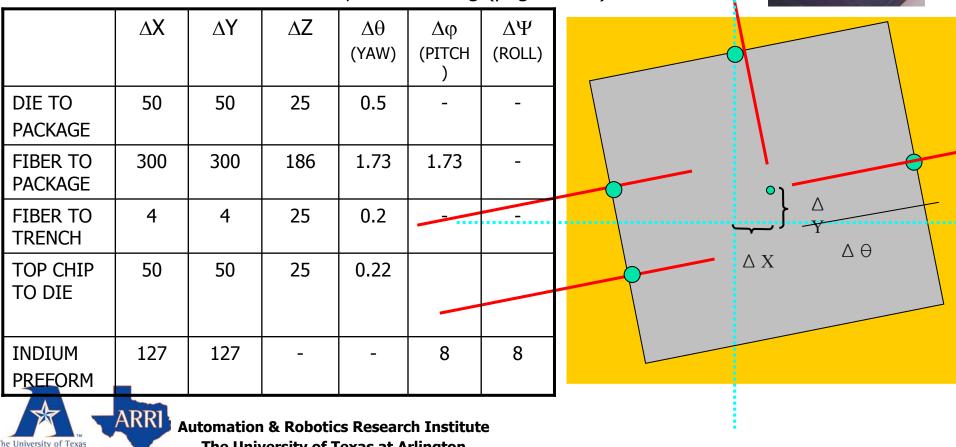




15 PI motorized DOF Station + 4 manual DOF

S&A MEMS: Tolerance Budget

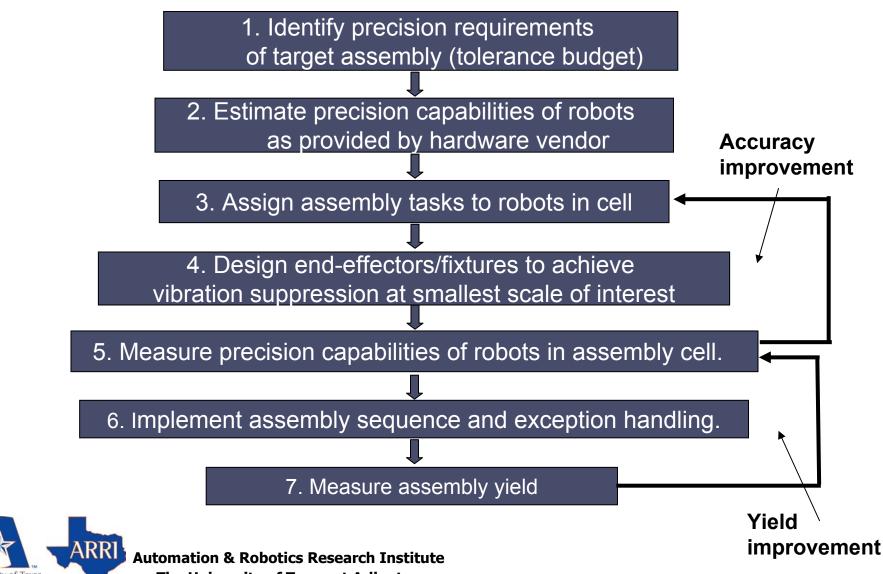
- Driving the precision requirements for this application:
 - Die to package: 50 μ m @ 0.5 deg
 - Fiber to package: 300 μ m @ 1.75 deg
 - Fiber to trench: 4 μ m @ 0.2 deg (peg in hole)



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Designing Multiscale Assembly Cells



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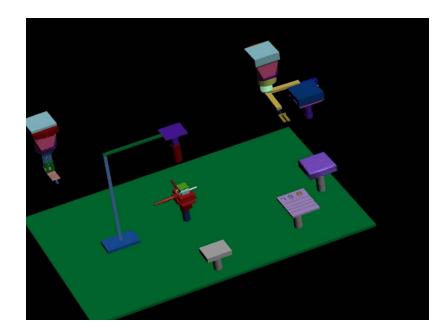
Multiscale System Design Rules Based on Accuracy/Repeatability/Resolution





Robot Assignment

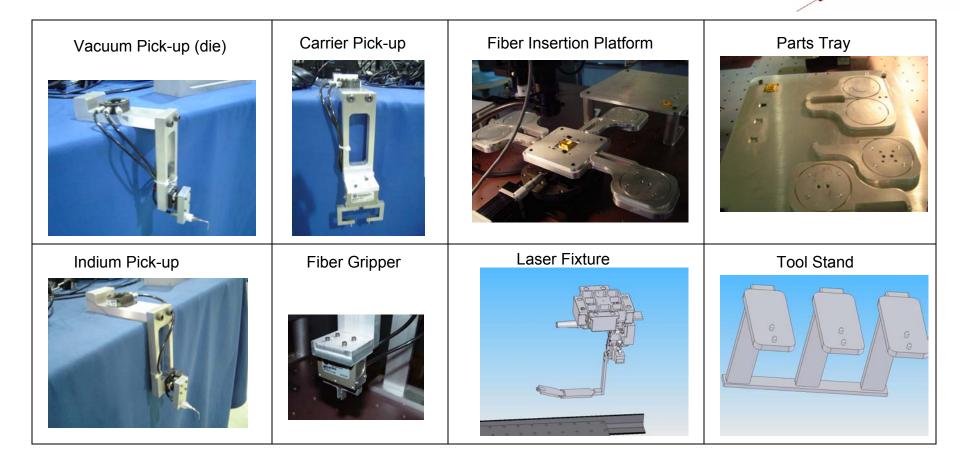
Manipulator	Tooling	Calibra-	Servo-	Fixture
or process		tion	ing	
COARSE I	Zoom	No	No	N/A
	camera			
COARSE II	Most	Yes	No	N/A
	tools			
FINE I	Laser	No	No	N/A
FINE II	Spool	Yes	Yes	N/A
	plate			
Fiber –	N/A	No	No	Yes
package				(pick &
insertion				place)
Fiber-trench	N/A	Yes	Yes	No
insertion				
Die	N/A	Yes	No	Yes
Pick/Place				(pick)
Package	N/A	Yes	No	Yes
Pick/Place				(pick)
Preform-	N/A	Yes	No	Yes
Package				(pick &
insertion				place)



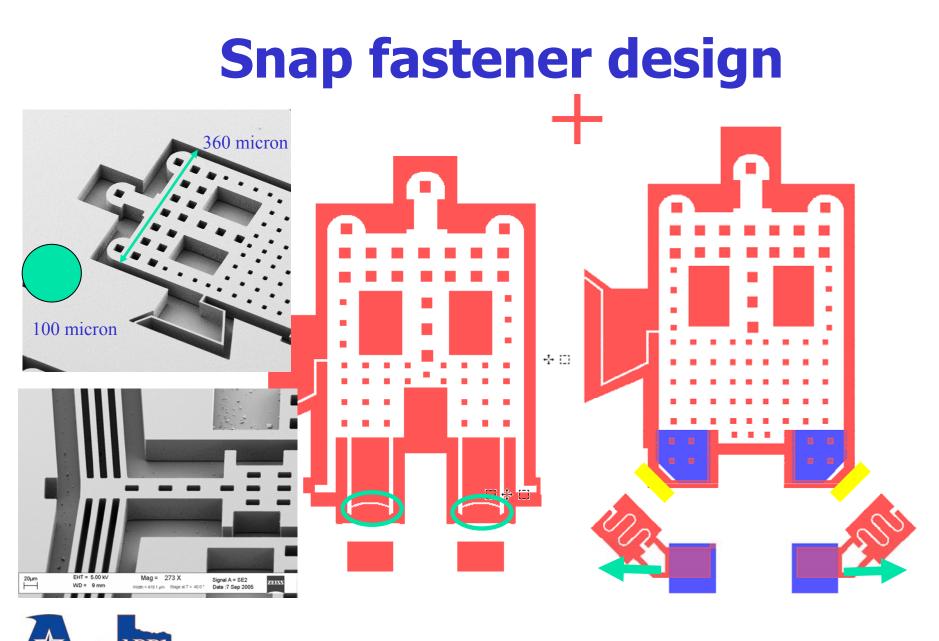


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Tools and End-Effectors





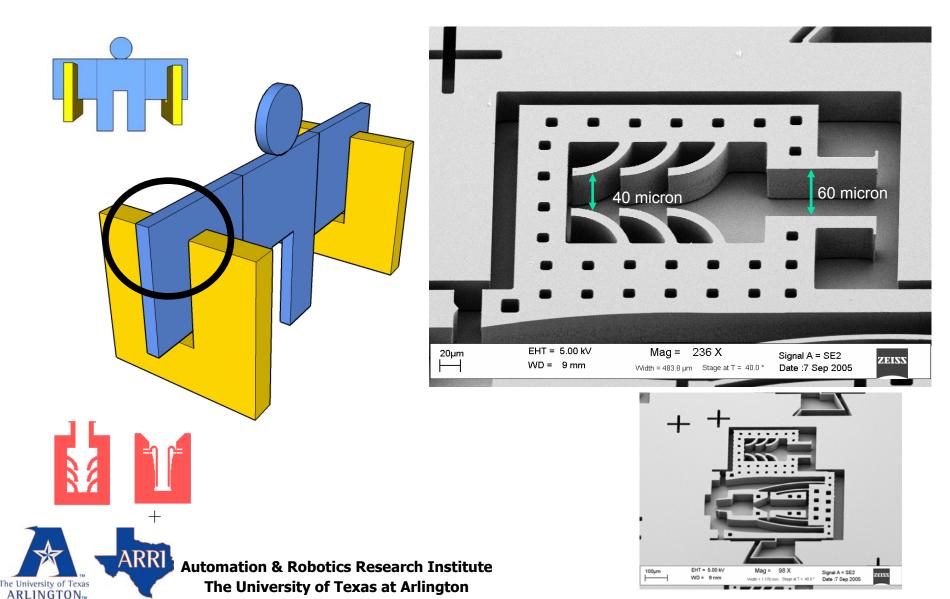


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3D Microstructures







Serial Assembly Scripting

Microassembly

Consecutive, Automated Assemblies

Assembly Yield: 90+% with well designed parts and appropriate tolerance and calibration precision



M³ in Operation



Packaging Sequence

Assembled MOEMS



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